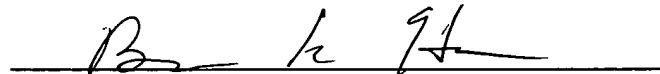


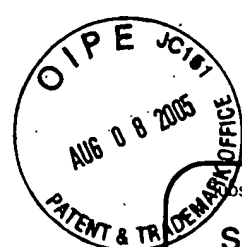
The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

The Commissioner is hereby authorized to charge the sum of \$180.00 due under 37 CFR § 1.17(p) pursuant to § 1.97, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/5699.P3/BKH.

Respectfully submitted,

A handwritten signature in black ink, appearing to read 'B K Hrma', is written over a horizontal line.

Brian K. Hrma
Registration No. 41,852
MOSER, PATTERSON & SHERIDAN, L.L.P.
3040 Post Oak Blvd. Suite 1500
Houston, TX 77056
Telephone: (713) 623-4844
Facsimile: (713) 623-4846
Attorney for Applicant(s)



Institute for form 1449A/PTO

**SUPPLEMENTAL INFORMATION
DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet 1 of 3

Complete if Known

Application Number	10/608,404
Filing Date	JUNE 26, 2003
First Named Inventor	LIU, et al.
Art Unit	1742
Examiner Name	MICHAEL P. ALEXANDER
Attorney Docket Number	AMAT/5699.P3/CMP/CMP/RKK

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
	A1	US-6,893,476	5/17/2005	6,893,476	
	A2	US-2001/0016469	8/23/2001	Chopra	
	A3	US-2001/0052351	12/20/2001	Brown, et al.	
	A4	US-2002/0016064	2/7/2002	Komai, et al.	
	A5	US-2002/0130049	9/19/2002	Chen, et al.	
	A6	US-2003/0115475	6/19/2003	Russo, et al.	
	A7	US-2003/0116446	6/23/2003	Duboust, et al.	
	A8	US-2003/0178320	9/25/2003	Liu, et al.	
	A9	US-2003/0216045	12/20/2003	Wang, et al.	
	A10	US-2003/0234184	12/25/2003	Liu, et al.	
	A11	US-2004/0053499	3/18/2004	Liu, et al.	
	A12	US-2004/0144038	07/29/2004	Siddiqui	
	A13	US-2004/0248412	12/9/2004	Liu, et al.	
	A14	US-2005/0044803	3/3/2005	Siddiqui, et al.	
	A15	US-2005/0076578	04/14/2005	Siddiqui, et al.	
	A16	US-2005/0076579	04/14/2005	Siddiqui, et al.	
	A17	US-2005/0079718	04/14/2005	Siddiqui, et al.	
	A18	US-2005/0079803	04/14/2005	Siddiqui, et al.	
	A19	US-2005/0565378	3/17/2005	Chen, et al.	

FOREIGN PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)				
	B1	EP 0 699 782	3/6/1996	Datta		
	B2	EP 1 167 585	1/2/2002	Hong		
	B3	JP 05 302199 (English abstract)	11/16/1993	Bridgestone Bekaert Steel		X
	B4	JP 06 158397 (English abstract)	6/7/1994	Asahi Glass Co Ltd		X
	B5	JP 10 121297 (English translation)	5/12/1998	Nippon Riironaale		X
	B6	JP 58-093886 (English abstract)	6/3/1983	Tokoyama Soda Co Ltd		X
	B7	JP 58-093899 (English abstract)	6/8/1983	Sumitomo Metal Land Ltd		X
	B8	JP 01-77117 (English translation)	3/23/2001	Takeshi, et al.		X
	B9	JP 2000 192298 (English abstract)	7/11/2000	Ebara		X
	B10	JP 2000 256898 (English abstract)	9/19/2000	Permelec Electrode Ltd		X
	B11	SU 1 618 538 (English abstract)	1/7/1991	Vladimir		X
	B12	WO 02/88229	11/7/2002	Beulich, et al.		
	B13	WO 02/75804	9/26/2002	Chen		
	B14	WO 02/23616	3/21/2002	Wang		

Examiner
SignatureDate
Considered

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO

**SUPPLEMENTAL INFORMATION
DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet **2** of **3****Complete if Known**

Application Number	10/608,404
Filing Date	JUNE 26, 2003
First Named Inventor	LIU, et al.
Art Unit	1742
Examiner Name	MICHAEL P. ALEXANDER
Attorney Docket Number	AMAT/5699.P3/CMP/CMP/RKK

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C1	International Search Report for PCT/US02/40754 dated August 5, 2003. (AMAT/5998PC)	
	C2	PCT International Search Report for PCT/US04/17691, dated November 16, 2004. (AMAT/5699.PC03)	
	C3	PCT Written Opinion for PCT/US04/17691, dated November 16, 2004. (AMAT/5699.PC03)	
	C4	Besser et al., "Mechanical Strain Evolution in Cu/low K Interconnect Lines", <i>Mat. Res. Soc. Symp. Proc.</i> Vol. 795, 2004 Materials Research Society, pp. U1.1.1-U1.1.6.	
	C5	Chandrasekaran, et al., "Effects of CMP Process Conditions on Defect Generation in Low-k Materials", <i>Journal of The Electrochemical Society</i> , pp. G882-G889 (2004).	
	C6	Chang, et al., "Microleveling Mechanisms and Applications of Electropolishing of Planarization of Copper Metallization", <i>J. Vac. Sci. Technol. B</i> 20(5), Sep/Oct 2002, pp. 2149-2152.	
	C7	Chang, et al., "Superpolishing of Planarizing Copper Damascene Interconnects", <i>Electrochemical and Solid-State Letters</i> , pp. G72-G74 (2003).	
	C8	Contolini, et al., "Electrochemical Planarization for Multilevel Metallization", <i>J. Electrochem. Soc.</i> , Vol. 141, No. 9, September 1994, pp. 2503-2510.	
	C9	Du, et al., "Mechanism of Copper Removal During CMP in Acidic H ₂ O ₂ Slurry", <i>Journal of The Electrochemical Society</i> , pp. G230-235 (2004).	
	C10	Hu, et al. "Copper Interconnection Integration and Reliability", <i>Thin Solid State Films</i> , pp. 84-92, (1995).	
	C11	Jin-Hua, et al., "An XPS and BAW Sensor Study of the Structure and Real-Time Growth Behaviour of a Complex Surface Film on Copper in Sodium Chloride Solutions (pH=9), Containing a Low Concentration of Benzotriazole", <i>Eletrochimica Acta</i> , Vol. 43, Nos 3-4, pp. 265-274, 1998.	

Examiner Signature		Date Considered	
--------------------	--	-----------------	--

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 120 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO		Complete if Known	
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)		Application Number	10/608,404
		Filing Date	JUNE 26, 2003
		First Named Inventor	LIU, et al.
		Art Unit	1742
		Examiner Name	MICHAEL P. ALEXANDER
Sheet 3 of 3	Attorney Docket Number	AMAT/5699.P3/CMP/CMP/RKK	

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C12	Kaufman, et al., "Chemical-Mechanical Polishing for Fabricating Patterned W Metal Features as Chip Interconnects", <i>J. Electrochem. Soc.</i> , Vol. 138, No. 11, November 1991; The Electrochemical Society, Inc. pp. 3460-3465.	
	C13	Kondo, et al., "Role of Additives for Copper Damascene Electrodeposition: Experimental Study on Inhibition and Acceleration Effects", <i>Journal of The Electrochemical Society</i> , pp. C250-C255 (2004)	
	C14	Padhi, et al., "Planarization of Copper Thin Films by Electropolishing in Phosphoric Acid for ULSI Applications", <i>Journal of the Electrochemical Society</i> , 150, pp. G10-G14 (2003).	
	C15	Qafsaoui, et al., "Quantitative Characterization of Protective Films Grown on Copper in the Presence of Different Triazole Derivative Inhibitors", <i>Electrochimica Acta</i> 47 (2002), pp. 4339-4346.	
	C16	Tamilmani, et al., "Potential-pH Diagrams of Interest to Chemical Mechanical Planarization of Copper", <i>Journal of The Electrochemical Society</i> , V. 149, pp. G638-G642 (2002).	
	C17	Tromans, et al., "Growth of Passivating CuBTA Films on Copper in Aqueous Chloride/Benzotriazole Solutions", <i>Electrochemical and Solid-State Letter</i> , V. 5, pp. B5-B8 (2002).	
	C18	Wang, et al., "Inhibition Effect of AC-Treated, Mixed Self-Assembled Film of Phenylthiourea and 1-Dodecanethiol on Copper Corrosion", <i>Journal of The Electrochemical Society</i> , pp. B11-B15 (2004).	

Examiner Signature		Date Considered	
--------------------	--	-----------------	--

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 120 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.